

Paper No. 2



Sheet 1 of 1

Form PTO-1449
(Rev. 2-88)

**INFORMATION DISCLOSURE STATEMENT
BY APPLICANT**

(Use several sheets if necessary)

Form PTO-1449 (Rev. 2-88)		U. S. DEPARTMENT OF COMMERCE PATENT AND TRADEMARK OFFICE	ATTY. DOCKET NO. APPLICATION NO. 5853-224 10/082,010
INFORMATION DISCLOSURE STATEMENT BY APPLICANT			
<i>(Use several sheets if necessary)</i>			
		FILING DATE 2/22/02	GROUP
U. S. PATENT DOCUMENTS			

U.S. PATENT DOCUMENTS

FOREIGN PATENT DOCUMENTS

DOCUMENT NUMBER	DATE	COUNTRY	CLASS	SUBCLASS	TRANSLATION	
					YES	NO

OTHER DOCUMENTS (Including Author, Title, Date, Pertinent Pages, Etc.)

		Stöber, W., et al. "Controlled Growth of Monodisperse Silica Spheres in the Micron Size Range", <i>Journal of Colloid and Interface Science</i> , Vol. 26 (1968), pgs. 62-69; and <i>Rosen, M.J., "Surfactants and Interfacial Phenomena"</i> John Wiley & Sons, 1989, pgs. 3-32, 52-54, 70-80, 122-132 and 398-401.
<i>L.J.W.</i>		
<i>L.P.M.E.</i>		

EXAMINER Symette T. May-Eminu DATE CONSIDERED 11/13/2003
* EXAMINER: Initial if a citation considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.

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U.S. DEPARTMENT OF COMMERCE
PATENT AND TRADEMARK OFFICEATTY. DOCKET NO.
5853-224APPLICATION NO.
10/082,010INFORMATION DISCLOSURE STATEMENT
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(Use several sheets if necessary)

APPLICANT
Singh et al.FILING DATE
02/22/2002GROUP
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AUG 21 2003

U.S. PATENT DOCUMENTS

EXAMINER'S INITIAL	DOCUMENT NUMBER	DATE	NAME	CLASS	SUBCLASS	FILING DATE IF APPROPRIATE
L.J.U-E	5,954,997	09/21/1999	Kaufman et al.	252	79,1	
L.J.U-E	6,454,819 B1	09/24/2002	Yano et al.	51	298	

FOREIGN PATENT DOCUMENTS

	DOCUMENT NUMBER	DATE	COUNTRY	CLASS	SUBCLASS	TRANSLATION	
						YES	NO

OTHER DOCUMENTS (Including Author, Title, Date, Pertinent Pages, Etc.)

L.J.U-E		Luo et al., "CHEMICAL-MECHANICAL POLISHING OF COPPER IN ACIDIC MEDIA," CMP-MIC Conference, 145-151, 1996					

EXAMINER Dynette J. Umeg-Euronic DATE CONSIDERED 11/5/2003

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